

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 108459	APPLICATION NO. NEW US PATENT APPLICATION 89/771,705	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT Kiichi UEYANAGI		
				FILING DATE January 30, 2001	AU-2653	
U.S. PATENT DOCUMENTS						
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
FOREIGN PATENT DOCUMENTS						
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)						
<i>(cc)</i>		J. Tominaga et al., "An approach for recording and readout beyond the diffraction limit with an Sb thin film", Applied Physics Letter, Vol. 73, No. 15, 1998, pp. 2078-2080				
<i>(cc)</i>		H. Fuji et al., "A near-field recording and readout technique using a reflective aperture in an optical disk", Tech. Dig. ISOM/ODS '99, TuD-29, 1999, pp.423-425				
<i>(cc)</i>		"Near-field Nanophotonics Handbook", The Optronics Co., Ltd., 1997, pp. 177-182				
EXAMINER	<i>Kim Chin</i>				DATE CONSIDERED 6/25/03	
Examiner:	Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.					